

ABSTRACT

SEMICONDUCTOR PROCESSING DEVICE AND METHOD FOR MONITORING WAFER POSITION STATUS

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A semiconductor processing device and a method for monitoring wafer position status are provided. The semiconductor processing device includes a detection device and a controller. The detection device is configured to detect in real time a real-time detected height value corresponding to each of a plurality of subregions distributed in an array, where a plurality of first subregions cover at least a slot in a base; the controller is configured to determine, according to the real-time detected height value corresponding to each of the first subregions and a preset reference height value, whether position status of the wafer is normal; the reference height value is a height value corresponding to each of the plurality of first subregions detected by the detection device when both the base and the wafer carried on the base are at a standard position. The semiconductor processing device and the method for monitoring wafer position status can more accurately reflect the position status of a wafer inside a process chamber.

20 Fig. 2